



PATENT  
Attorney Docket No. 02887.0257-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Akira HAMAGUCHI et. al. ) Group Art Unit: 2624  
Application No.: 10/687,828 ) Examiner: Vikkram BALI  
Filed: October 20, 2003 ) Confirmation No.: 2967  
For: METHOD AND APPARATUS FOR )  
DETERMINING DEFECT )  
DETECTION SENSITIVITY DATA, )  
CONTROL METHOD OF DEFECT )  
DETECTION APPARATUS, AND )  
METHOD AND APPARATUS FOR )  
DETECTING DEFECT OF )  
SEMICONDUCTOR DEVICES )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**REPLY TO OFFICE ACTION**

In reply to the Office Action mailed January 25, 2007, the period for response having been extended to July 25, 2007 by a request for extension of three months and fee payment filed concurrently herewith, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims in this paper.

**Remarks/Arguments** follow the amendment sections of this paper.